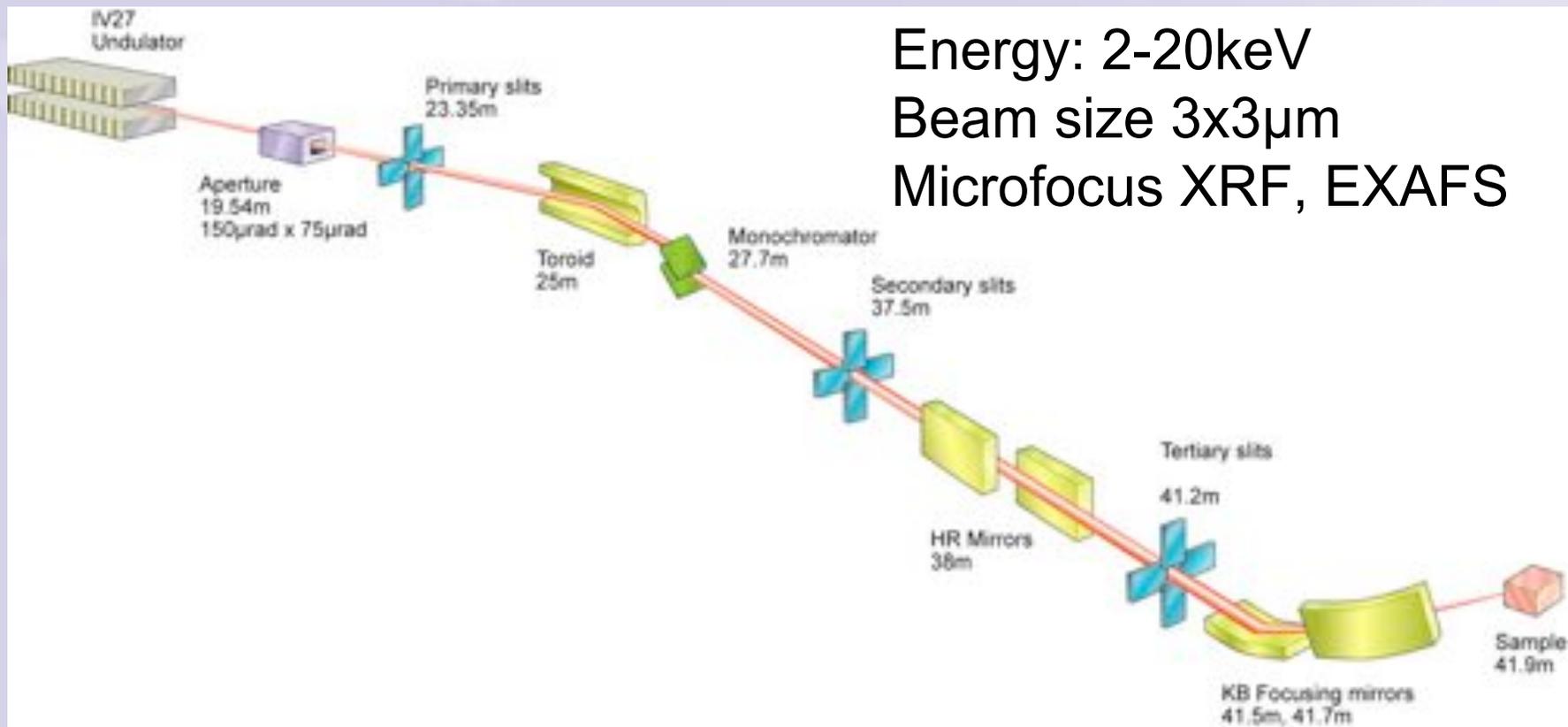


Bimorph mirrors – Performance and optimization on the microfocus spectroscopy beamline at Diamond

P. Quinn



I18 – Beamline overview



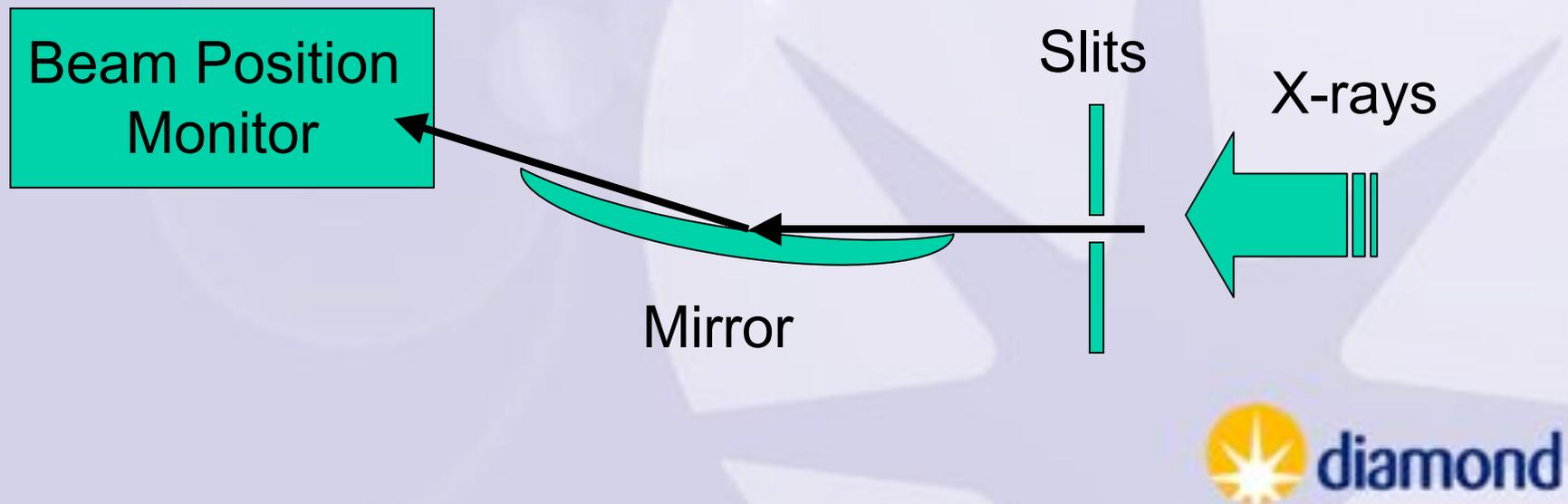
KB System

- SESO Mirrors
 - Vertical mirror
 - 200mm long
 - 8 electrodes
 - Horizontal mirror
 - 150mm long
 - 8 electrodes
 - Mirrors :
 - Silica 2.5 mm thick
 - Cr, Pt and Pd stripes (~50-60nm)
- Oxford Danfysik (FMB) power supply and motion control
- Operated in He for first year then switched to vacuum



Focusing on the beamline

- In-situ optimization – Pencil beam technique



Focusing on the beamline

- Scan across mirror recording beam position
- For each piezo
 - Increment the voltage
 - Rescan the mirror
 - Store the differential metrology
- Builds an interaction matrix, solve

Focusing on the beamline

- Limited to 5-7 microns:
 - Attempted various schemes, longer acquisition, different settling times, etc.
- Reasons:
 - Nonlinearity of mirror
 - Experimental limitations:
 - Short mirror requires narrow slit and small movements of slits
 - sampling
 - Power supply

Additional optimization

- Difficulty getting good focus using Interaction Matrix method
- Alternative approach:
 - Try to minimize the FWHM of the beam

Additional optimization

Principle:

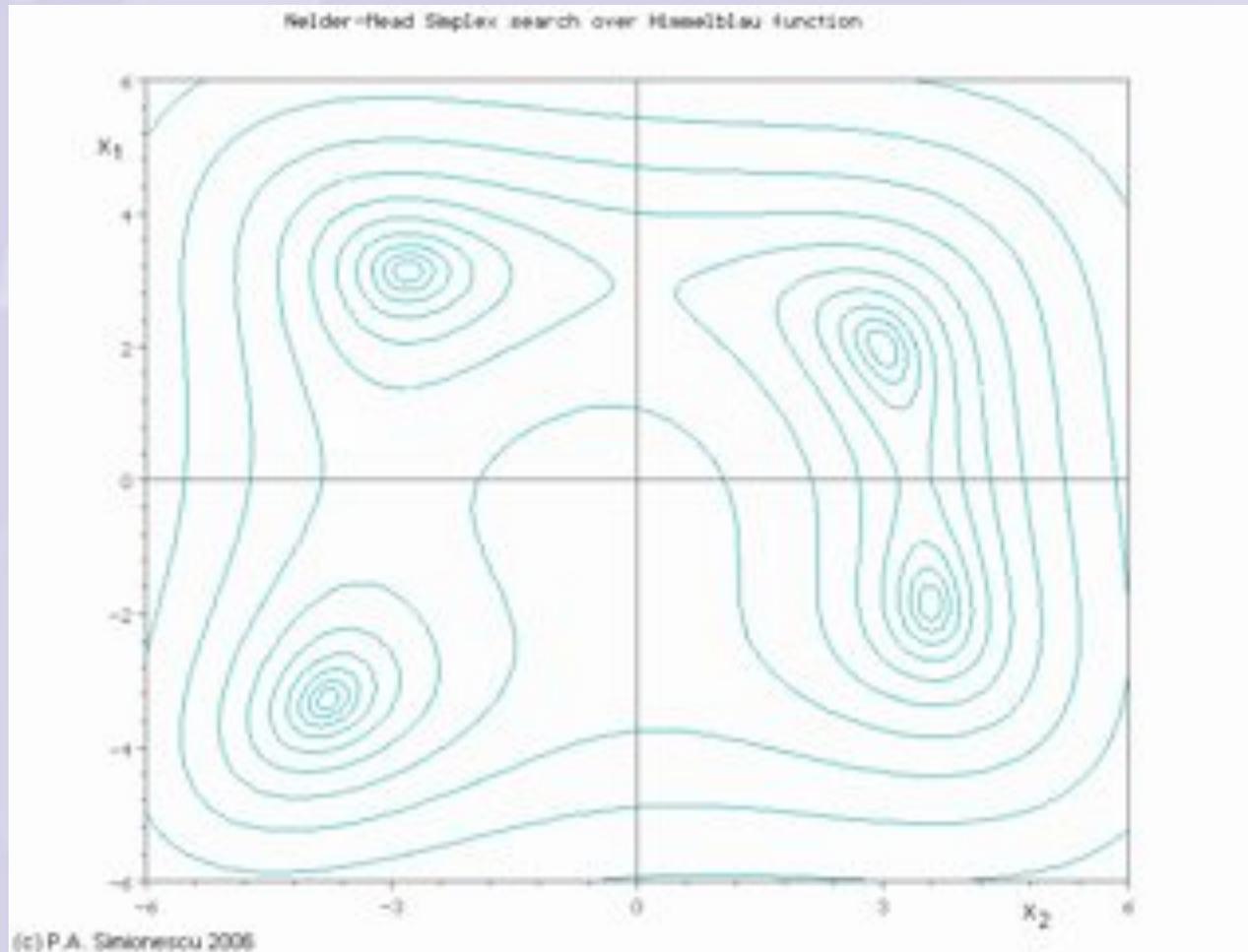
- Determine beam profile (knife edge scan)
- Observe changes in profile with voltage change
- Adjust mirror voltages to reduce profile

Optimization

Choice of algorithm:

- Gradient based algorithms can be problematic
 - How to choose step size for gradient ?
 - Slightly noisy data (always some noise in the profile)
- Pattern search - stencil type algorithm better
 - Non-gradient based
 - User defined initial voltage changes, gradually reducing to smaller step sizes
 - Noise tolerant
- Nelder Mead optimization

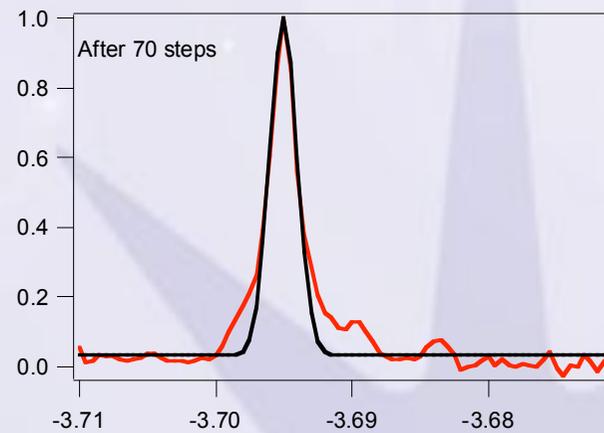
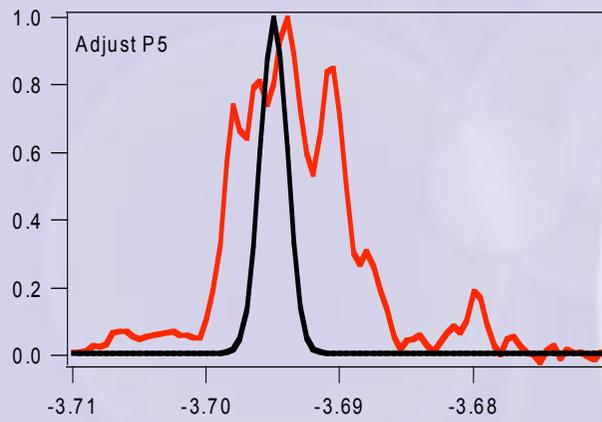
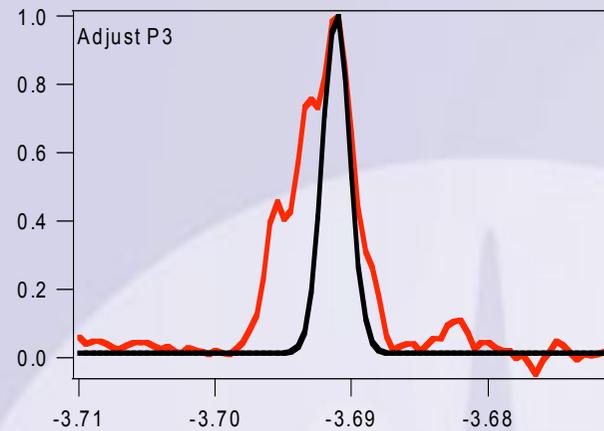
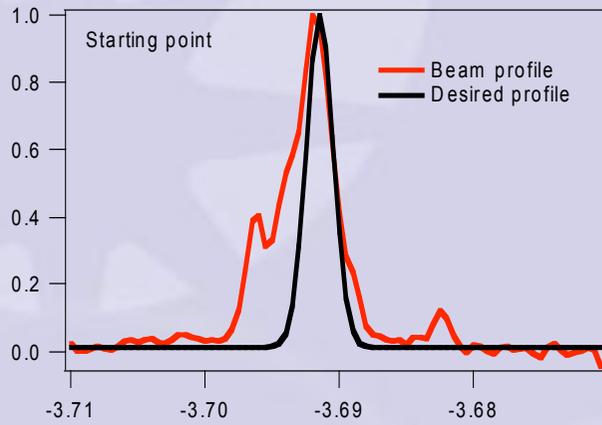
Nelder Mead - example



What to minimize ?

- Initially started with reducing FWHM
 - Doesn't guarantee nice shape
- Minimize difference between beam profile and a desired “model” function, e.g. gaussian

In progress



Bimorph Optimization

- Achieve 3 micron focus
- Run takes 2-3 hours to optimize
- If could replace knife edge scans with an x-ray eye would be quicker

Focusing on the beamline

- Problems:
 - Focusing takes too long:
 - User runs typically 3 days
 - Stability:
 - Focus not maintained : frequent re-focusing required
 - Beam movement?
 - Focus degrades over user run

Bimorph – Degraded ?

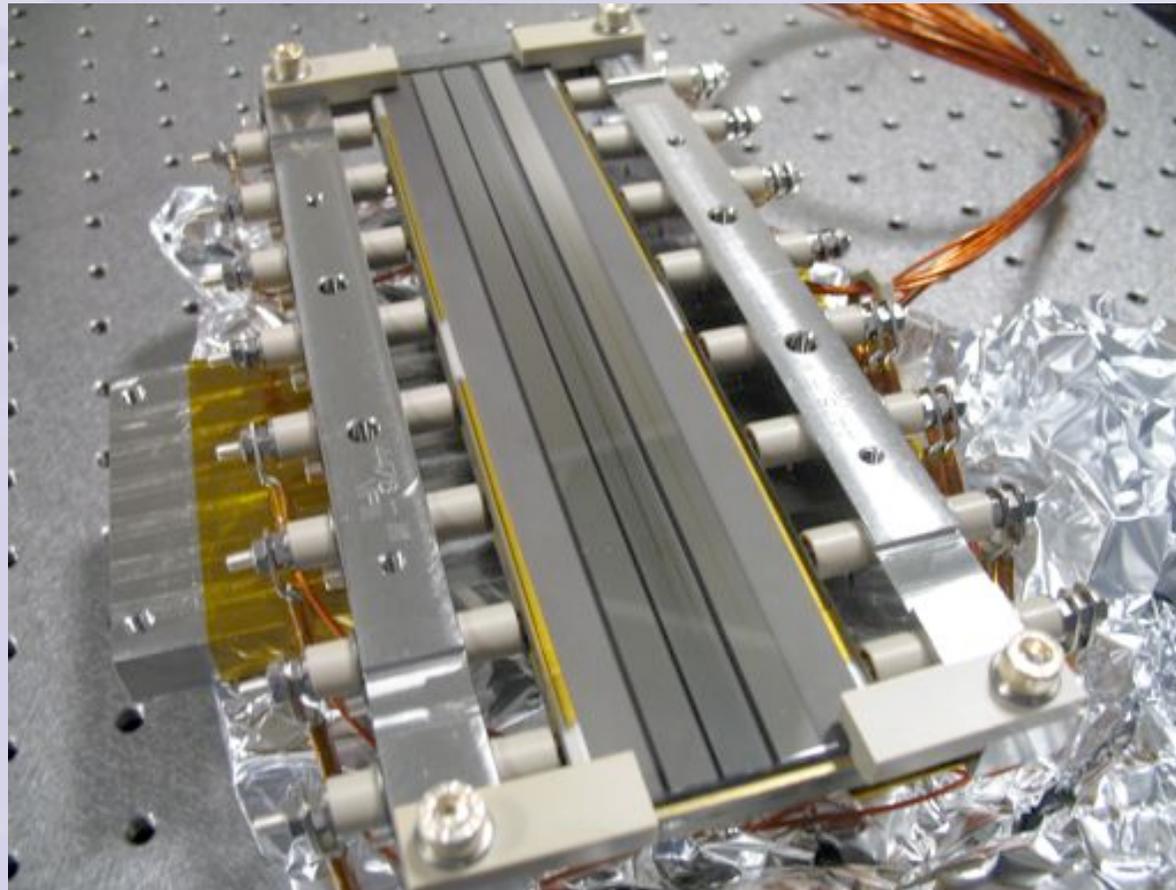
- Best focus currently around 3 microns:
 - Should be 1 micron based on specification/slope errors
- Initially had large beam vibrations:
 - 2 micron rms
 - Gradually reduced vibrations but focus not improving
- Visible streaking on central mirror stripe
- Remove vertical mirror for testing (Aug 08)

Bimorph tests

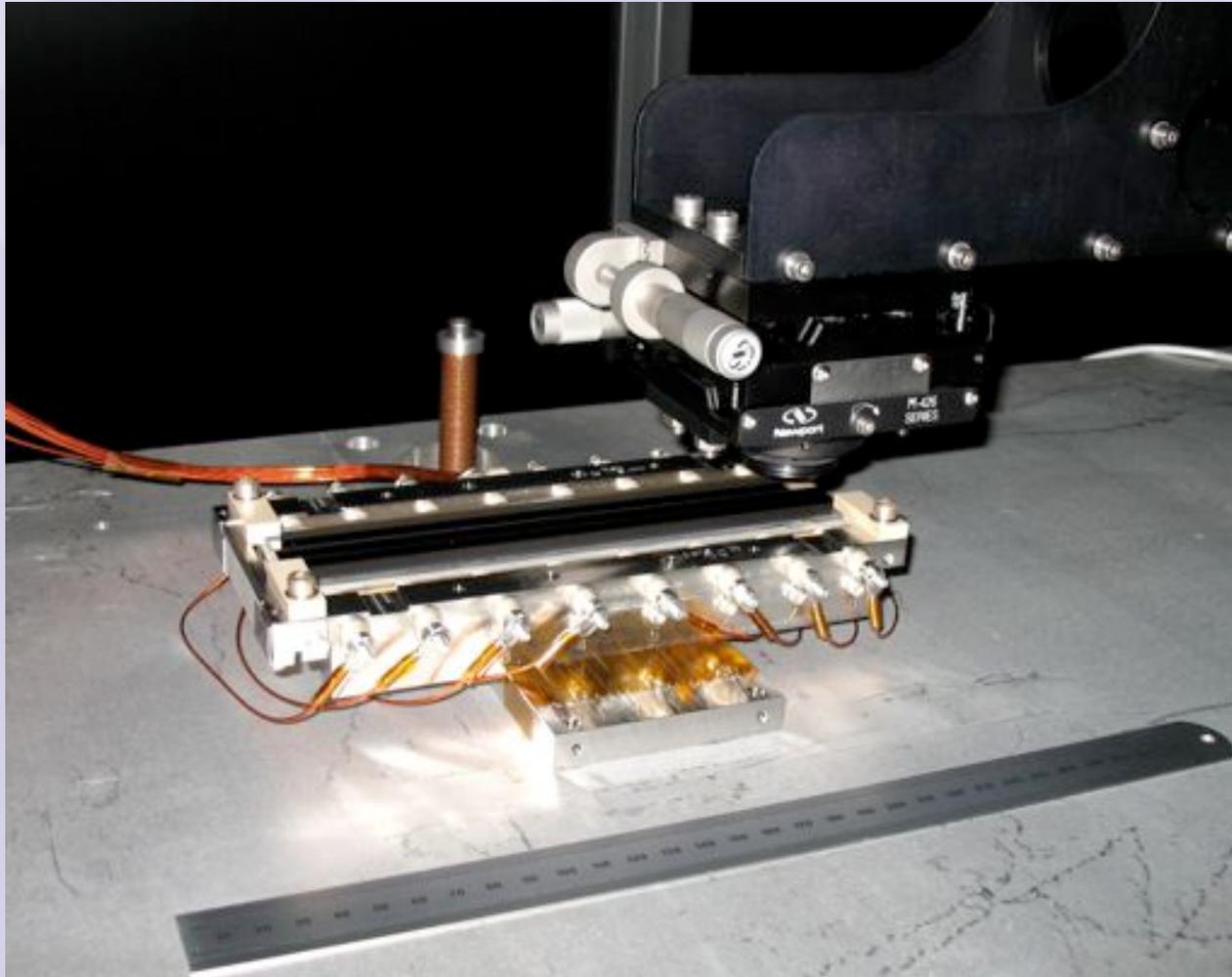
Vertical mirror
200mm long

150 mm central block

Additional electrode
at each end



Bimorph tests



SMP

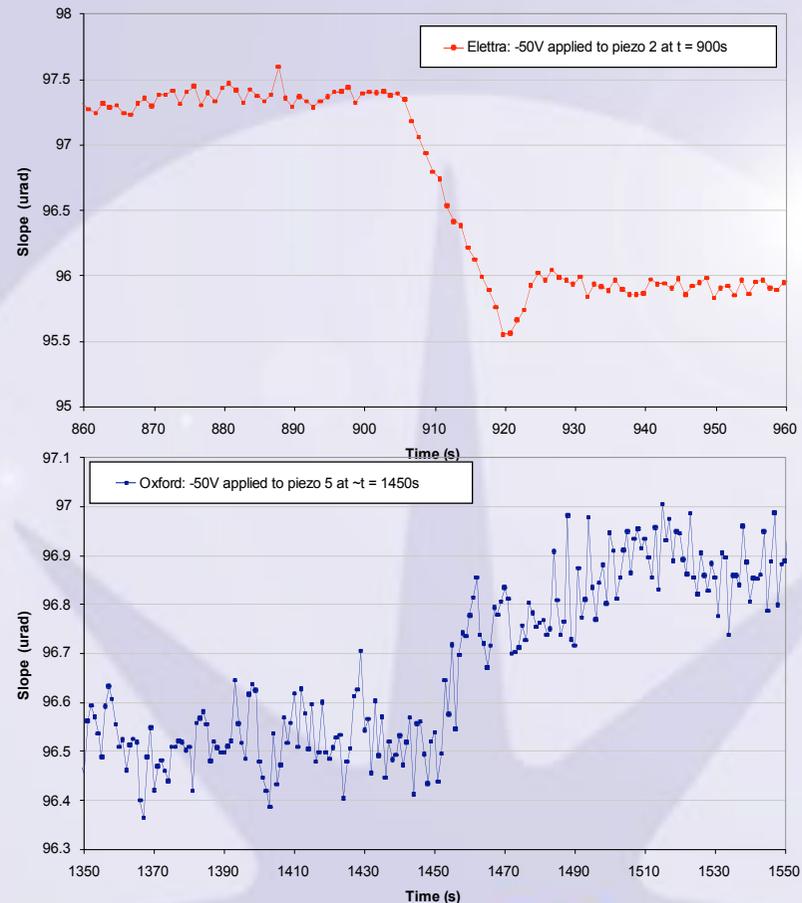
Diamond
Metrology lab

S. Alcock

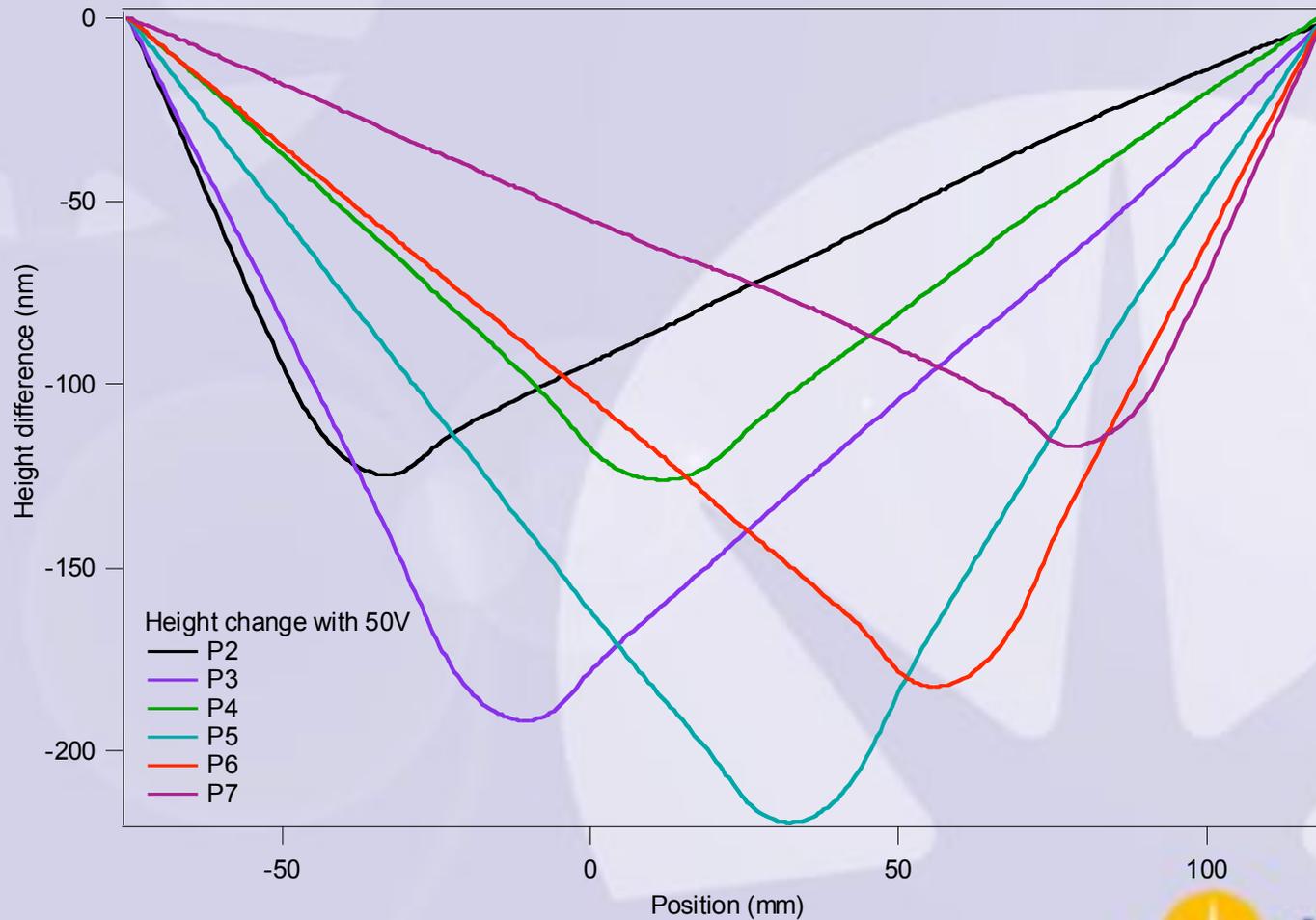
Bimorph tests

OD and Elettra
power supplies

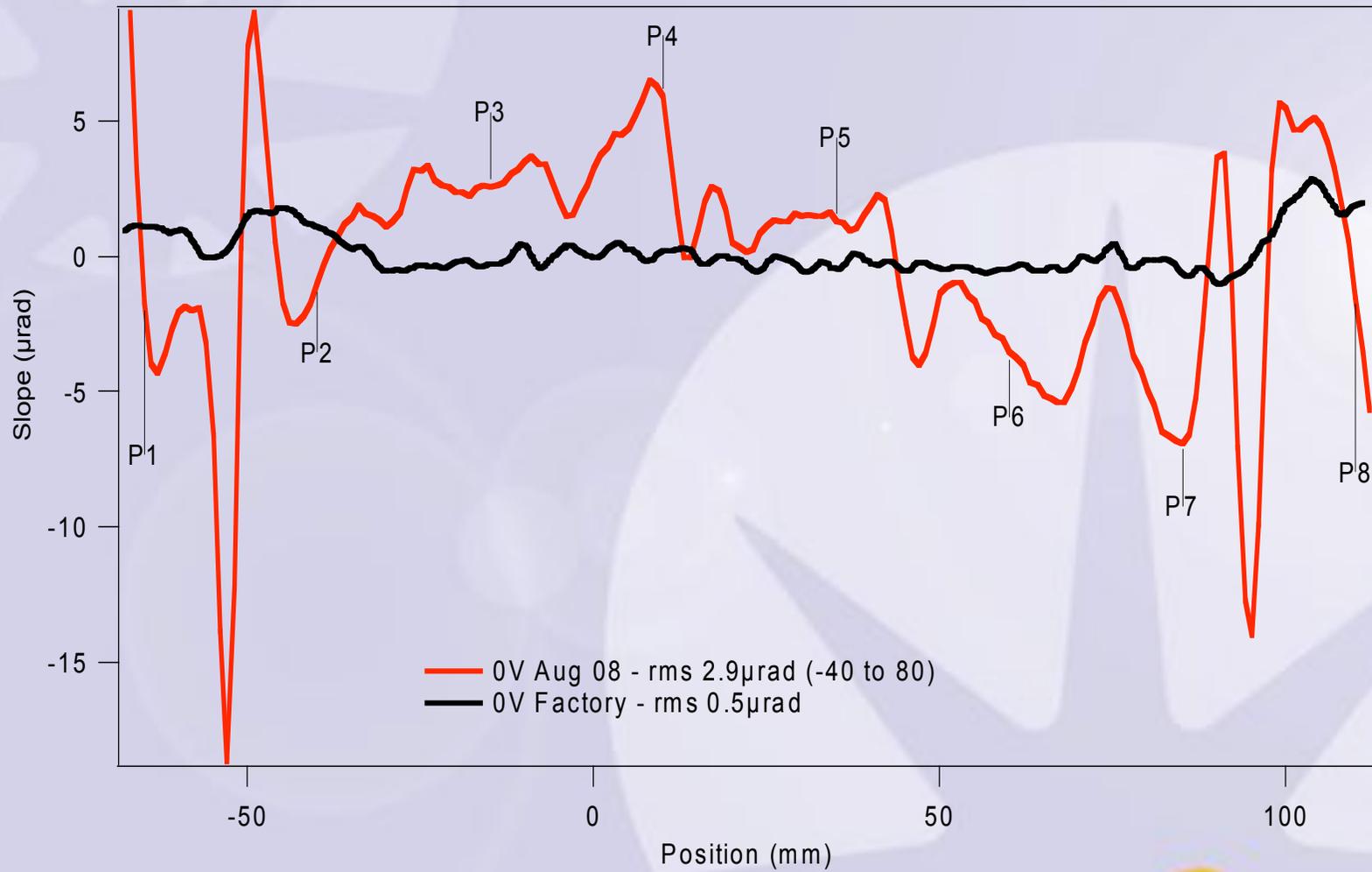
- Comparable stability
- Comparable settling times



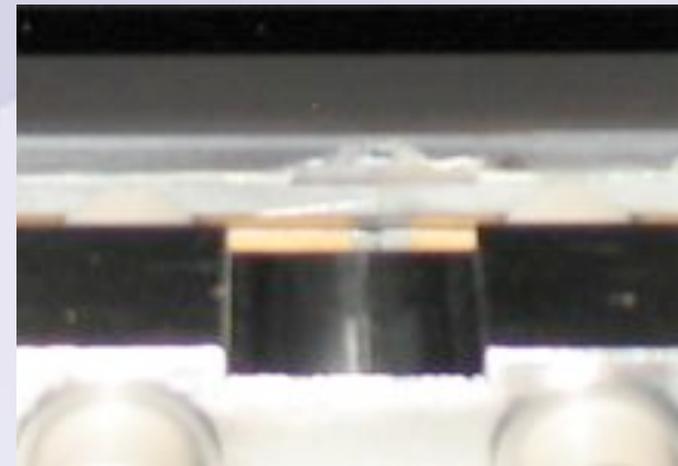
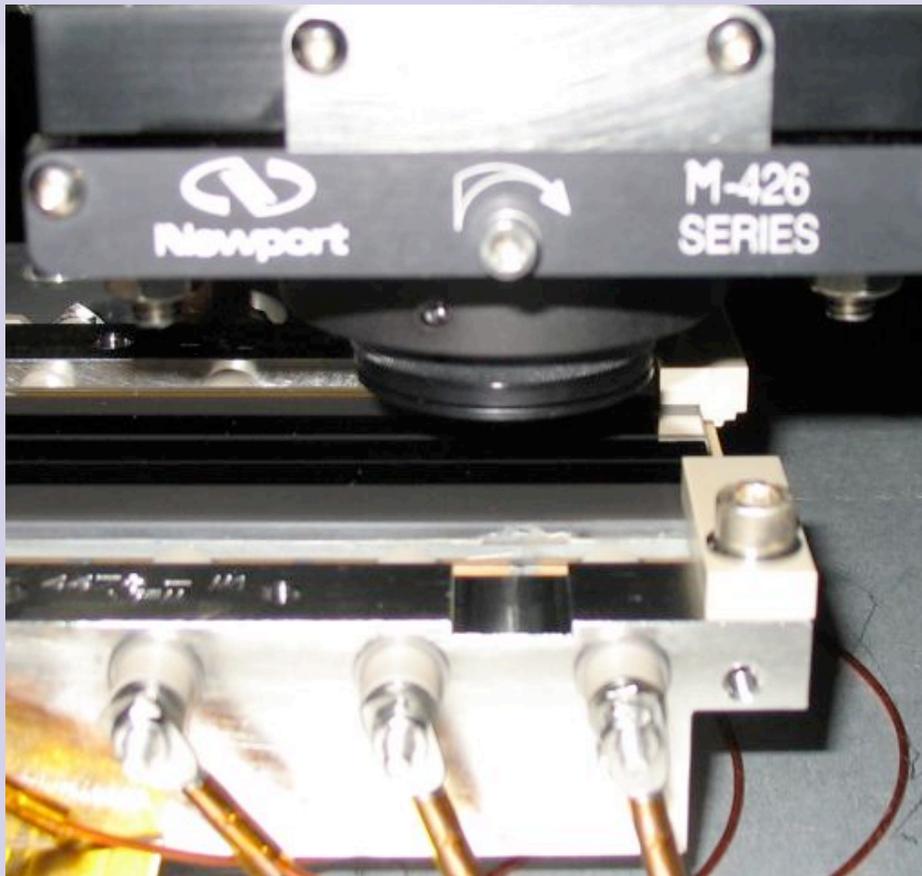
Bimorph Tests



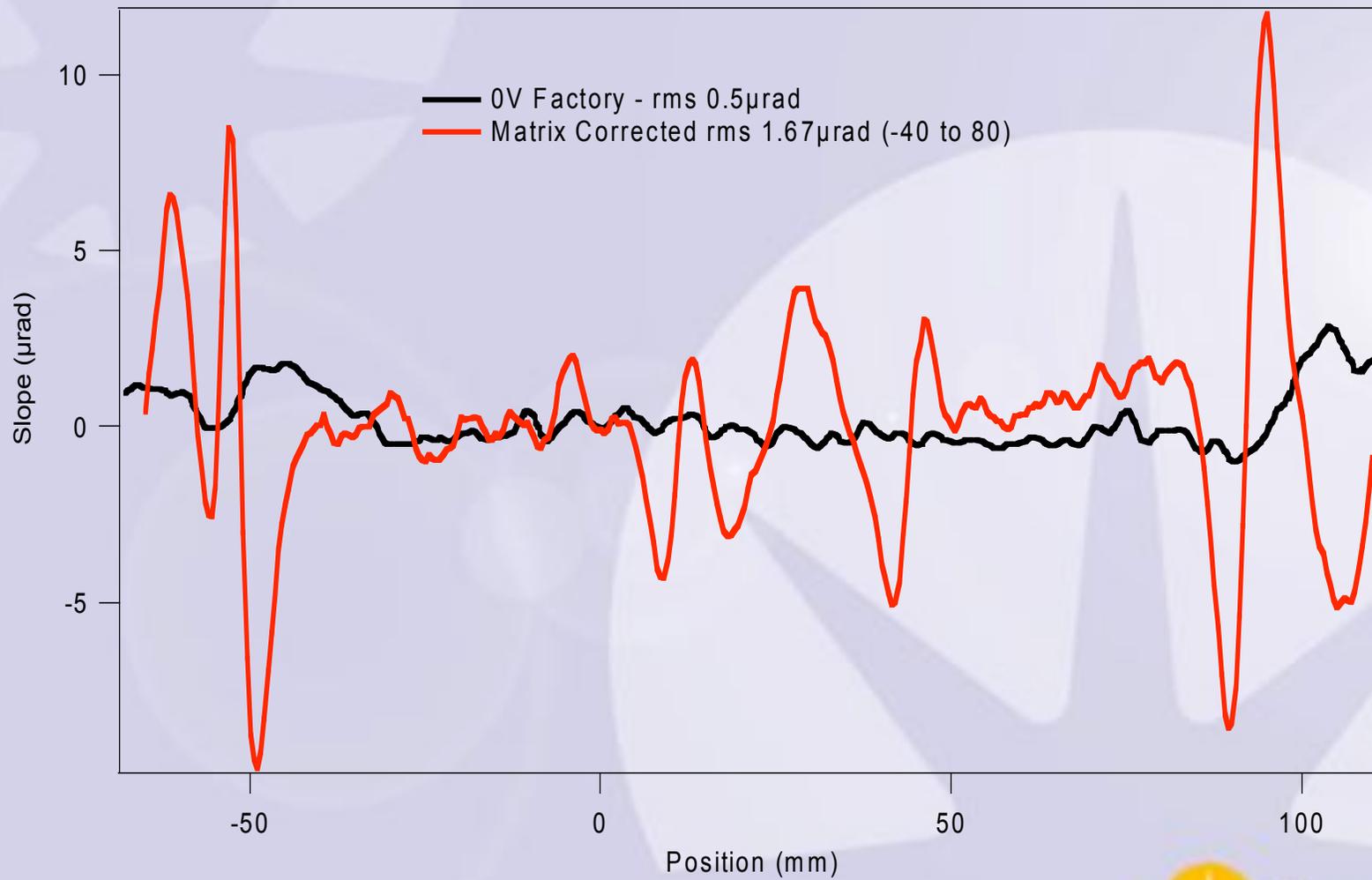
Slope errors



Slope errors



Slope errors



Slope errors

- Similar on all 3 stripes
 - Only 2 stripes used on beamline : substrate?
- $1.5 \mu\text{rad}$ slope error = 3 micron beam
(Shadow calculations)
- Central 120mm of mirror can be used.

Slope errors

Causes?:

- Interlock system : Switches off power with pressure
- Glue
- Frequent re-focusing

Conclusions

- Developed alternative methodology for focussing
- Mirror slope errors have gotten worse.
 - Need to replace the mirror to achieve 1micron spot but will it degrade again?

